



PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of

Docket No: Q64059

Shigeo ISHIKAWA

Appln. No.: 09/832,093

Confirmation No.: 8684

Group Art Unit: 2823

Filed: April 11, 2001

Examiner: Khiem D. Nguyen

For: FILM FORMING METHOD IN WHICH FLOW RATE IS SWITCHED

AMENDMENT UNDER 37 C.F.R. § 1.114(c)

MAIL STOP RCE

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

Sir:

The following are submitted herewith:

1. A petition and fee for a two month extension of time to extend the time period for responding to the Office Action dated August 1, 2003, to January 2, 2004 (January 1, 2004, being a Federal holiday);
2. Request for Continued Examination (RCE) and fee; and
3. Statement of Substance of Interview.

Please amend the above-identified application as follows on the accompanying pages.

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